PDMS Microfluidic Device Fabrication

Dr Ziyi Yu

Abstract

A protocol used to generate a PDMS microfluidic chip. Work was funded by Cambridge Synthetic Biology Strategic Research Initative (SRI) SynBio Fund.

http://www.synbio.cam.ac.uk/synbiofund

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Guidelines

Materials

- SU-8 photoresist (MicroChem, SU-8 2025)
- Propylene glycol monomethyl ether acetate (PGMEA; Sigma-Aldrich, cat. no. 537543)
- Poly(dimethyl siloxane) (PDMS) and curing agent (Dow Corning, Sylgard 184)
- Silicon wafers (3-inch diameter, Type-P, 1S polished; University Wafer, cat. no. S3P01SP)
- Isopropanol (Sigma-Aldrich, cat. no. 278475)
- 1H,1H,2H,2H-Perfluorododecyltrichlorosilane (Sigma-Aldrich, cat. no. 729965)
- HFE-7500 (3M, cat. no. 98-0212-2928-5)
- Pico-Surf (TM) 1, 10ml, 5% in Novec 7500 (Dolomite, cat. No. 3200214)

- Miltex® BIOPSY PUNCH WITH PLUNGER 1.0mm (Williams Medical Product Code D6345 Mfg. Code SCH-33-31AA-P)
- Hamilton gas-tight syringe, 0.5 ml (Hamilton, cat. no. 201300)
- TUBING,POLY,20PE,30m (Harvard apparatus, cat. no. 59-8324)
- Petri dishes (100 mm diameter × 15 mm
- Glass slides (75 × 50 mm)
- Scalpel
- Sharp tweezers

Before start

1. Use AutoDesk AutoCAD to design the microfluidic pattern printed on a photolithography mask.
2. Order photolithograph masks from Microlitho Services (http://www.microlitho.co.uk/)

Protocol

Step 1.

Use SU8 2025 for the master of the microfluidic device. To make the microfluidic device with 50 µm deep channel, follow the manufacturer's processing guidelines available online (http://www.microchem.com/Prod-SU8_KMPR.htm).

Step 2.

Place the wafer into the spin coater and dispense 5 ml of SU-8 2025 onto the centre of the silica

wafer.

Step 3.

Start the spin coater with the following program: 5 s at 500 rpm and thereafter 40 s at 1450 rpm.

Step 4.

Prebake the spin-coated silica wafer by placing it on a 65 °C.

Step 5.

Bake the silica wafer at 95 °C.

DURATION
00:06:00

Step 6.

Leave the silica wafer substrate to cool to room temperature.

Step 7.

Place the photolithograph mask on top of the substrate and expose the silica wafer with UV light from MJB4 for 7.5s (exposure energy 10 mJ cm^{-2}).

Step 8.

Incubate the silica wafer substrate on a 65 °C hot plate.

DURATION
00:01:00

Step 9.

Transfer the silica wafer substrate to a 95 °C hot plate and incubate.

DURATION

00:03:00

Step 10.

Leave the silica wafer substrate to cool to room temperature.

Step 11.

Immerse the wafer into the PGMEA liquid and make sure it is completely covered by developer.

DURATION
00:04:00

Step 12.

Rinse the wafer with isopropanol and then dry the silica wafer with nitrogen.

Step 13.

To improve the adhesion of SU-8 to the silica substrate, place the silica wafer on a 170 °C hot plate.

DURATION
00:05:00

Step 14.

Place the completed master silica wafer in a plastic Petri dish.

Step 15.

Weigh 30 g of PDMS base and 3 g of curing agent (10:1 ratio) and mix well.

Step 16.

Pour the PDMS mixture into the Petri dish about 6 mm deep and place the Petri dish in a vacuum desiccator to remove the bubbles.

Step 17.

Bake the PDMS in a 65 °C oven.

DURATION
04:00:00

Step 18.

Cut PDMS slab with a scalpel and gently peel the PDMS from the silicon wafer.

Step 19.

Use a biopsy punch to create hole for the fluid inlet and outlet.

Step 20.

Place the PDMS slab and the glass slide in the plasma chamber with the channel side facing upward.

Step 21.

Using the following settings to treat both PDMS slab and the glass slide with oxygen plasma. power = 1

DURATION
00:00:10

Step 22.

Gently bring plasma-treated slab and the glass slide together so that all parts are sealed to the glass.

Step 23.

Place the microfluidic device in a 110 °C oven.

DURATION
02:00:00

Step 24.

Leave the microfluidic to cool to room temperature.

Step 25.

Use 1% (vol/vol) perfluorododecyltrichlorosilane in Novec 7500 solution to fill the microfluidic channel.

Step 26.

Place the microfluidic device in a 65 °C oven.

DURATION
12:00:00

Step 27.

Leave the microfluidic to cool to room temperature and cover with Scotch tape to keep dust from the openings.